

Fig. 1

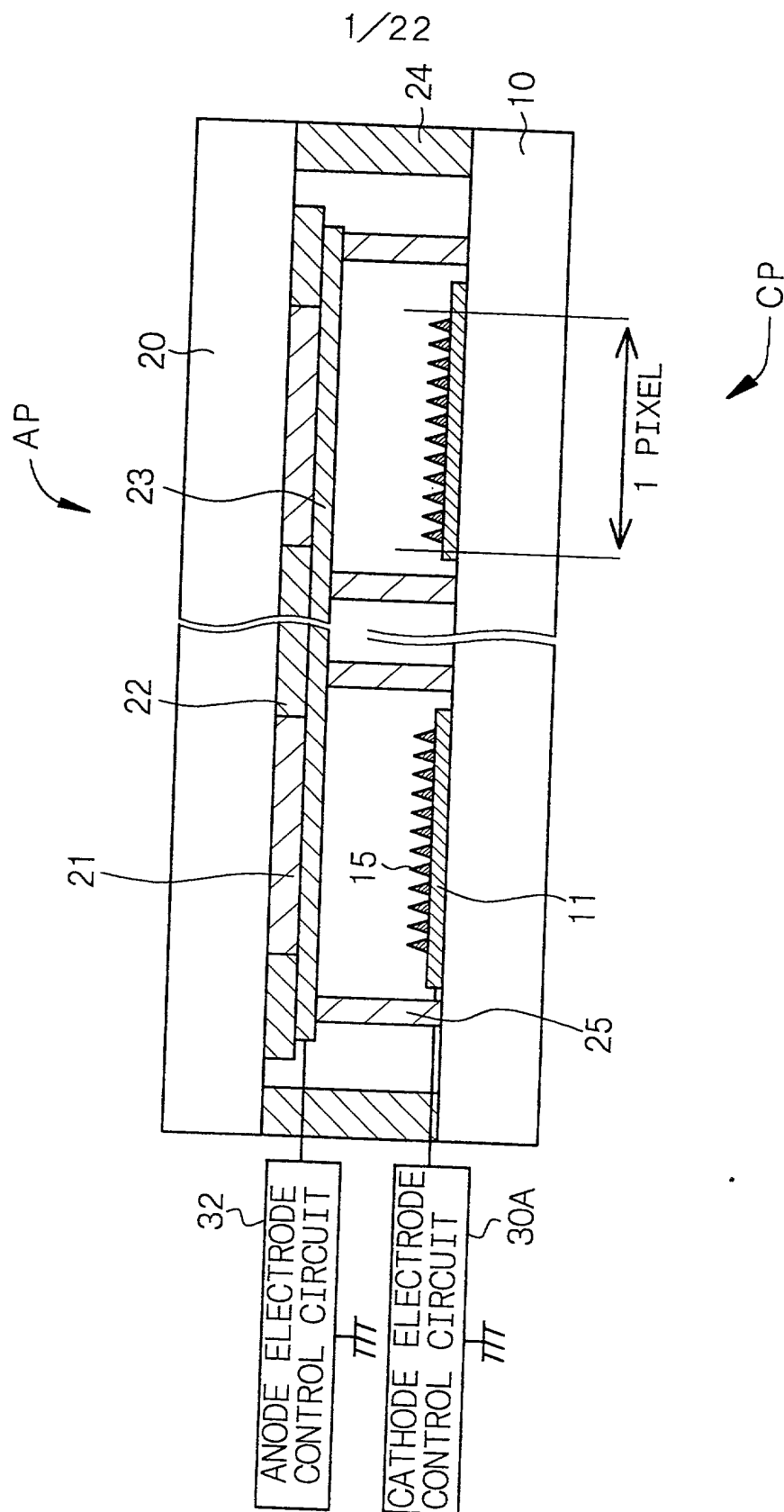


Fig. 2

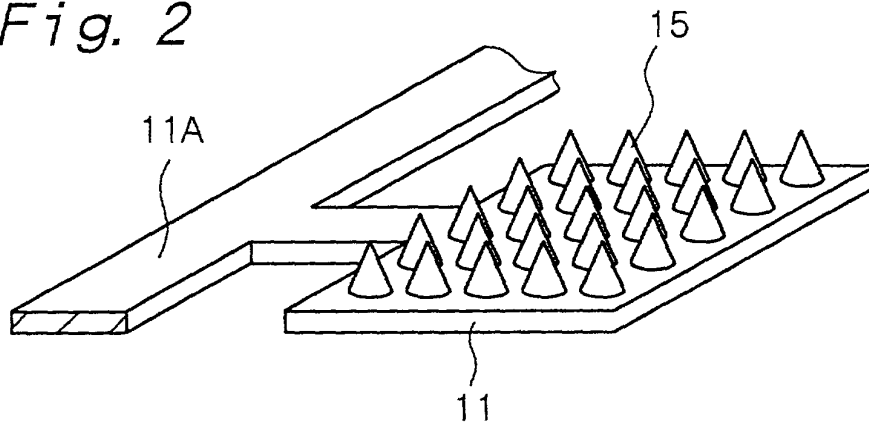


Fig. 3A

[STEP-100]

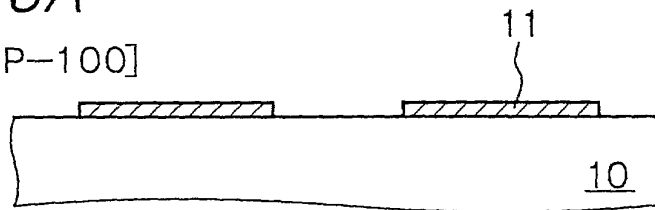


Fig. 3B

[STEP-110]

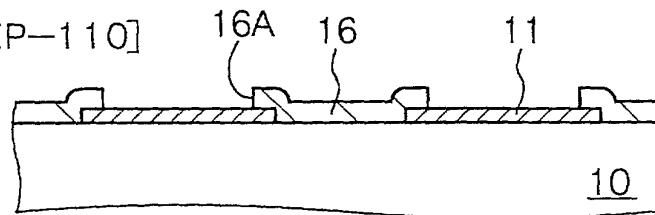
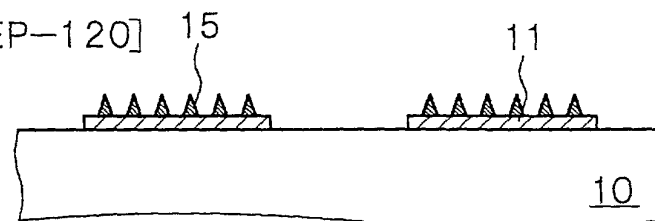


Fig. 3C

[STEP-120]



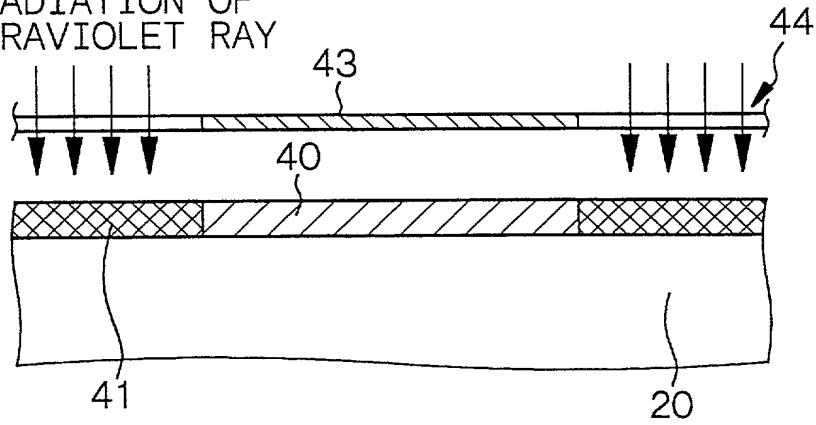
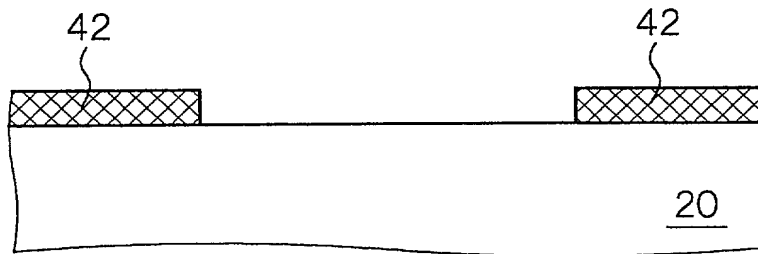
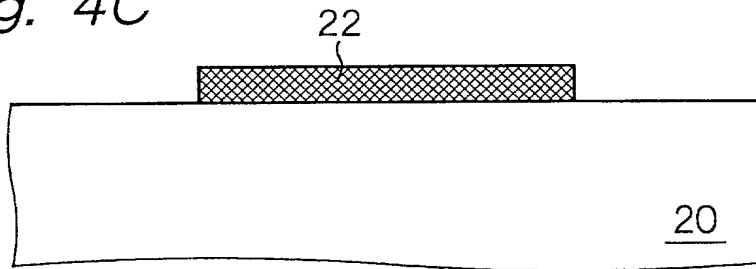
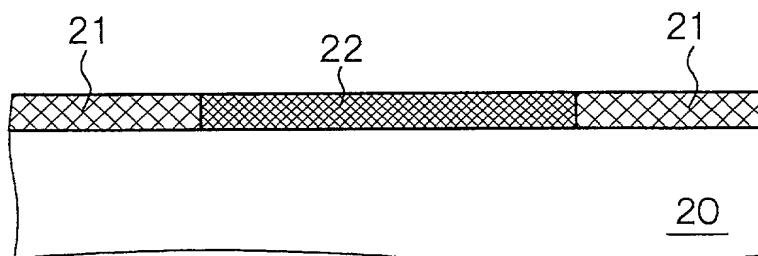
*Fig. 4A*IRRADIATION OF
ULTRAVIOLET RAY*Fig. 4B**Fig. 4C**Fig. 4D*

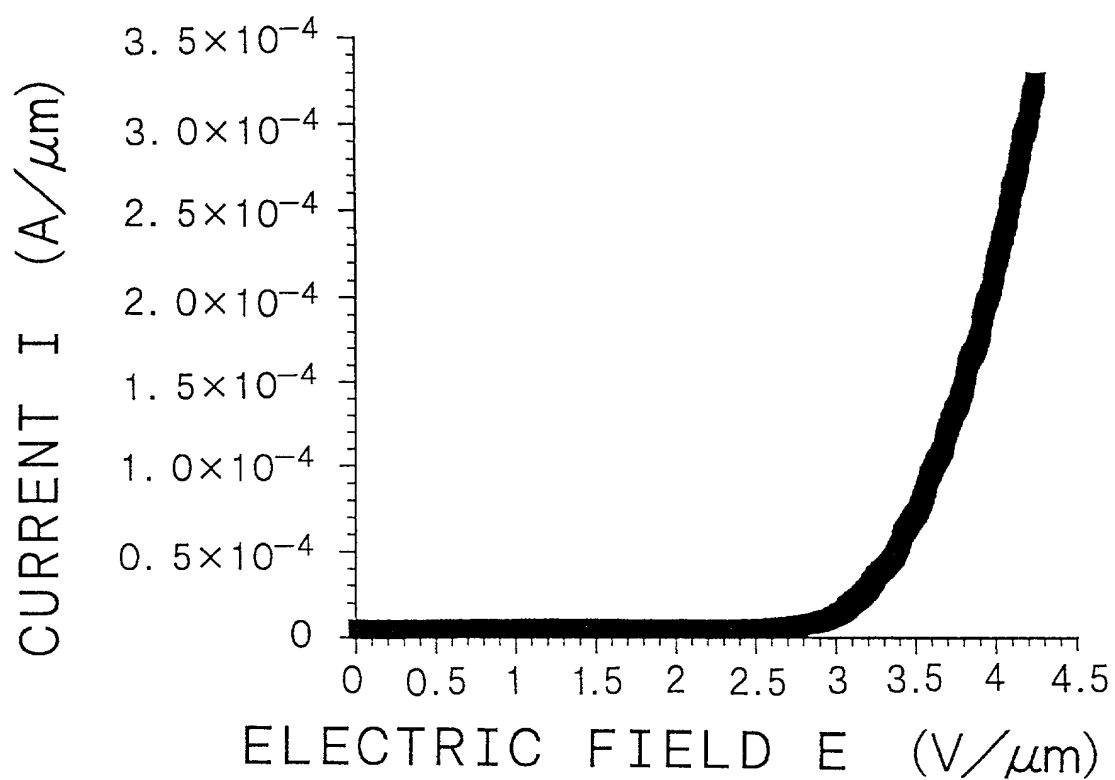
Fig. 5

Fig. 6A

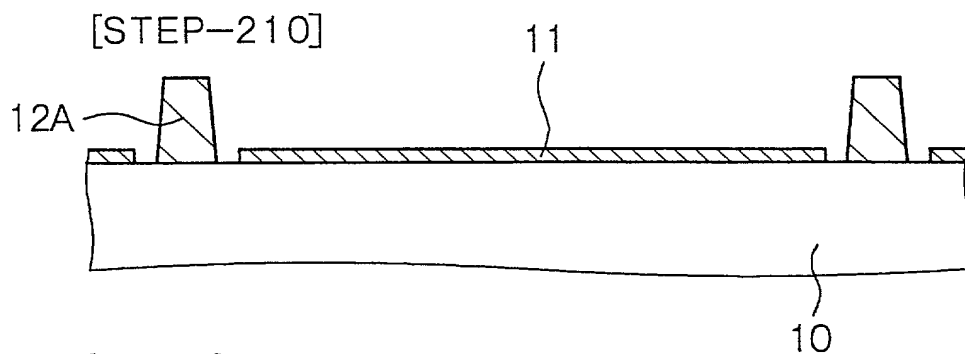


Fig. 6B

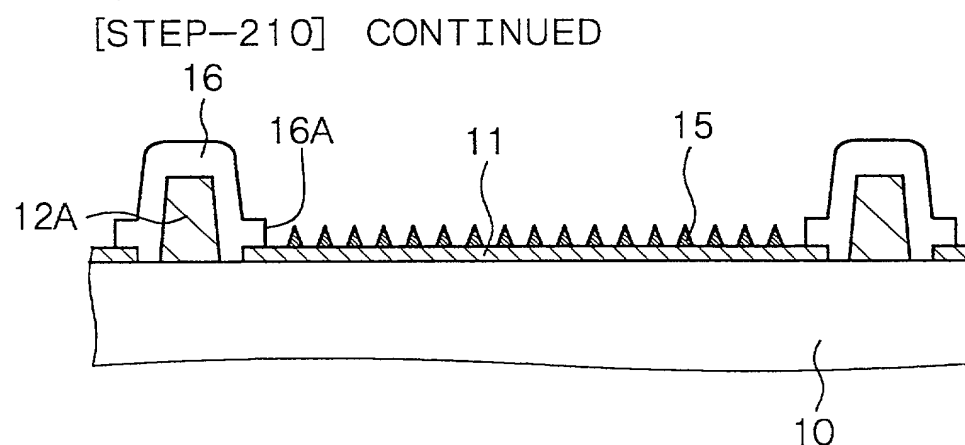


Fig. 6C

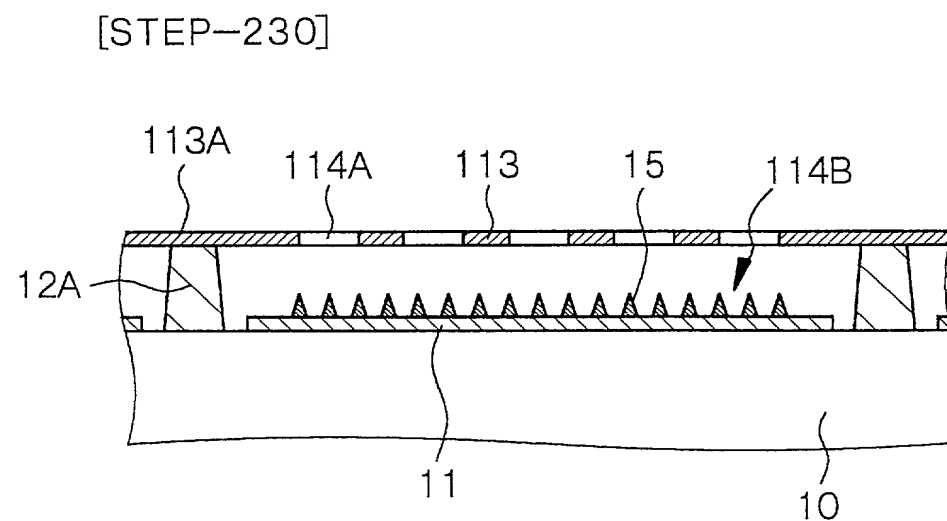


Fig. 7

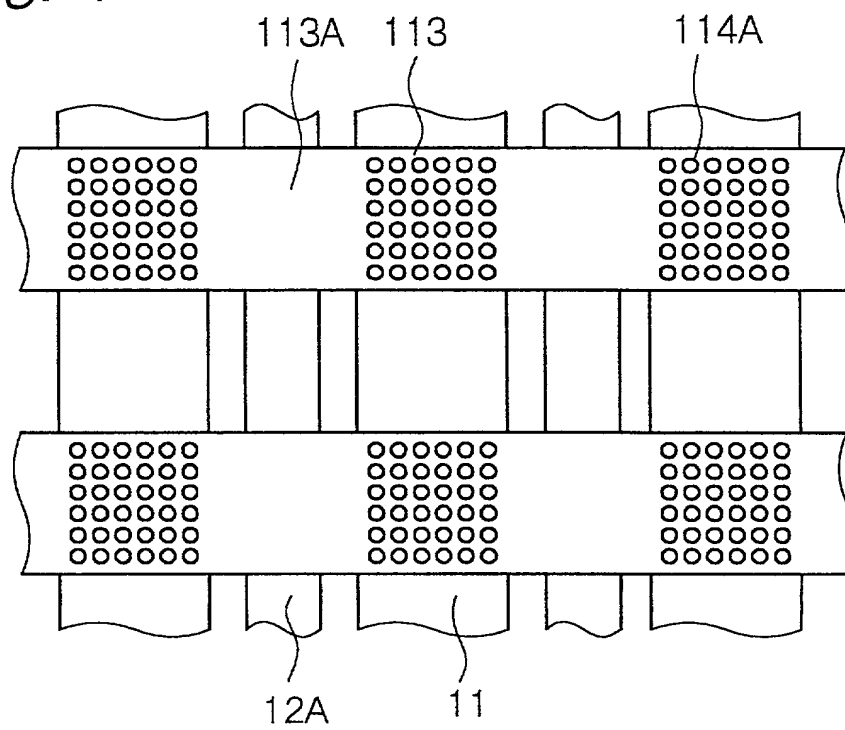
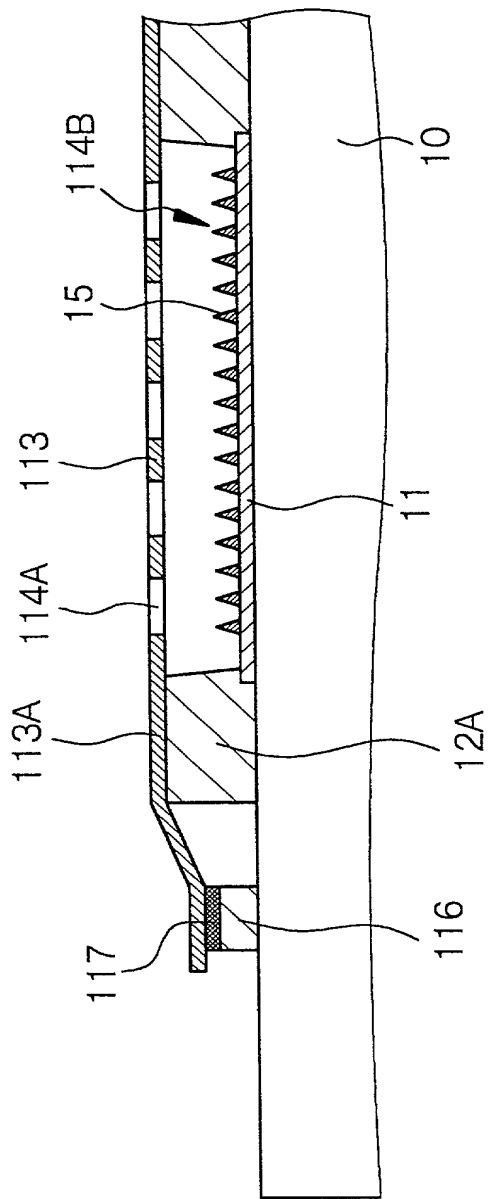


Fig. 8



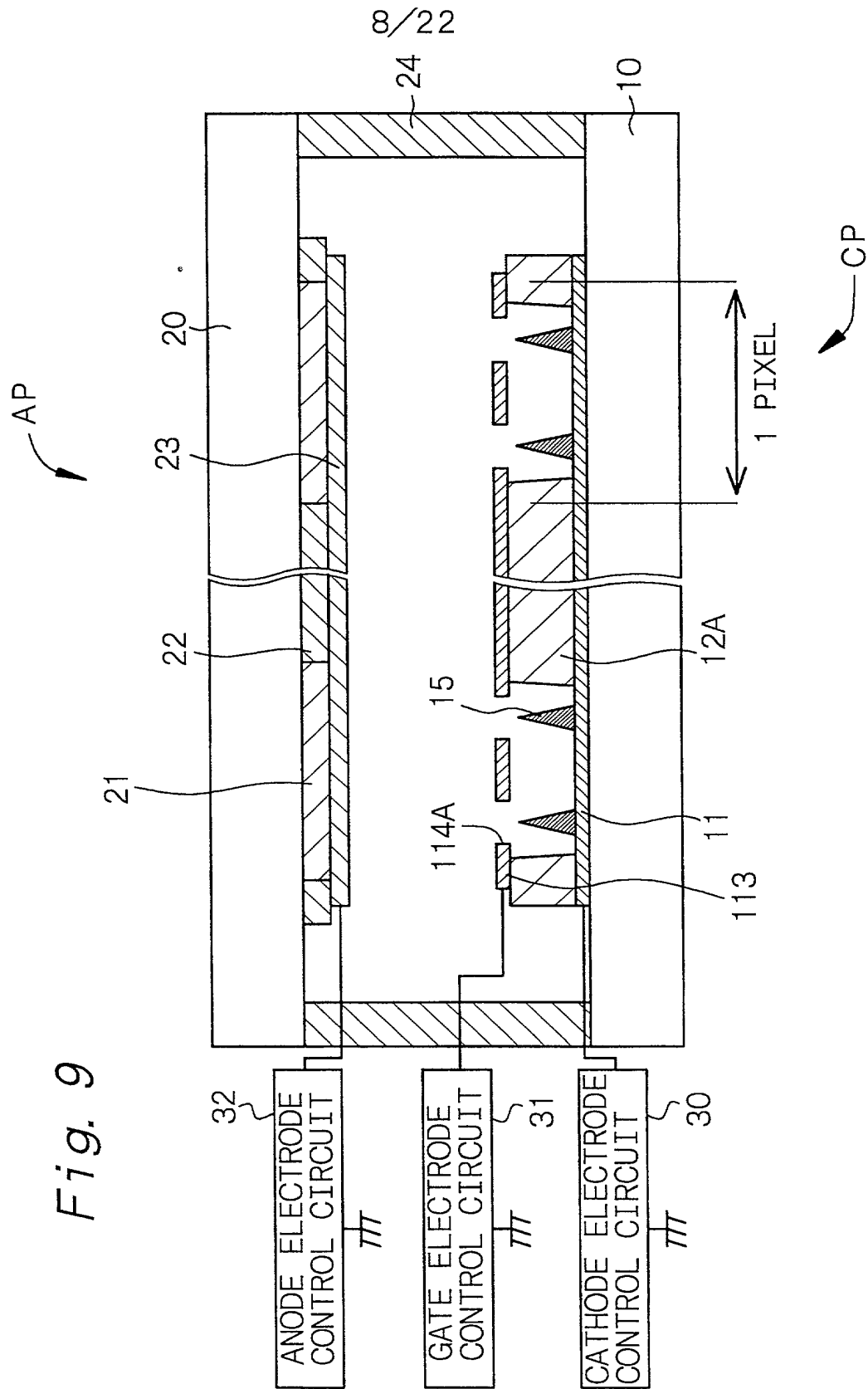


Fig. 10A

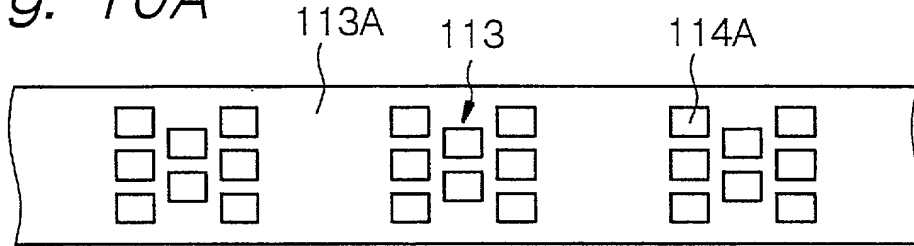


Fig. 10B

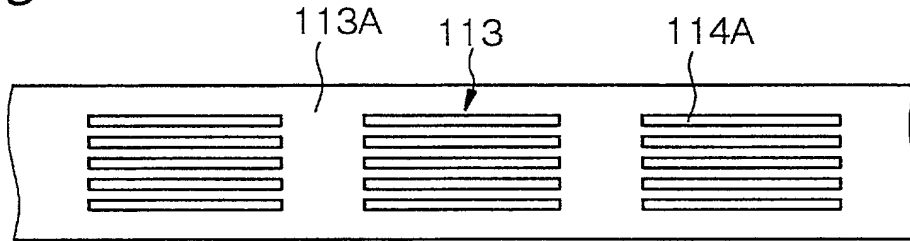


Fig. 10C

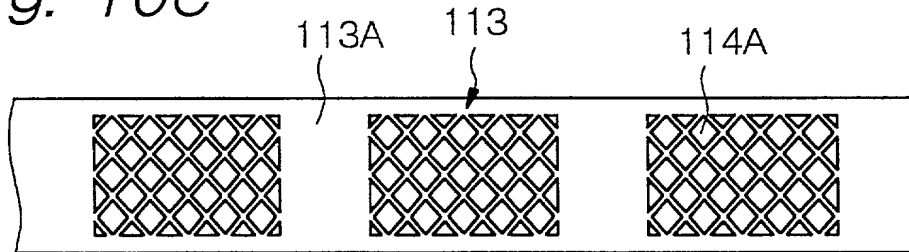
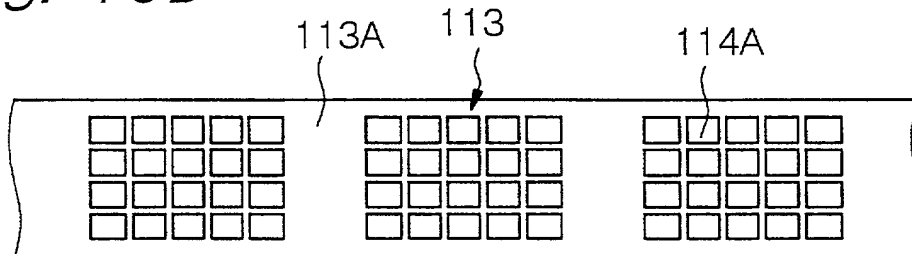


Fig. 10D



10/22

Fig. 11A
[STEP-310]

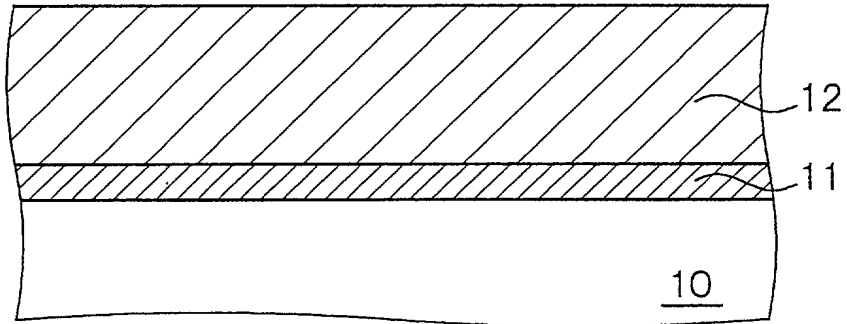


Fig. 11B
[STEP-330]

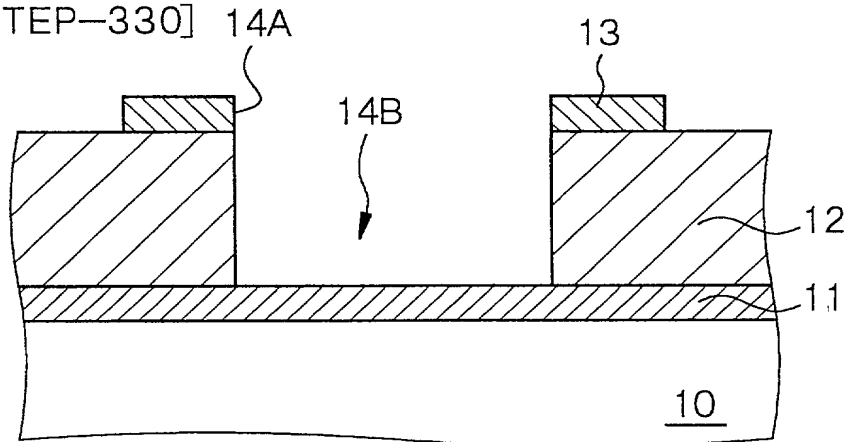


Fig. 11C
[STEP-340]

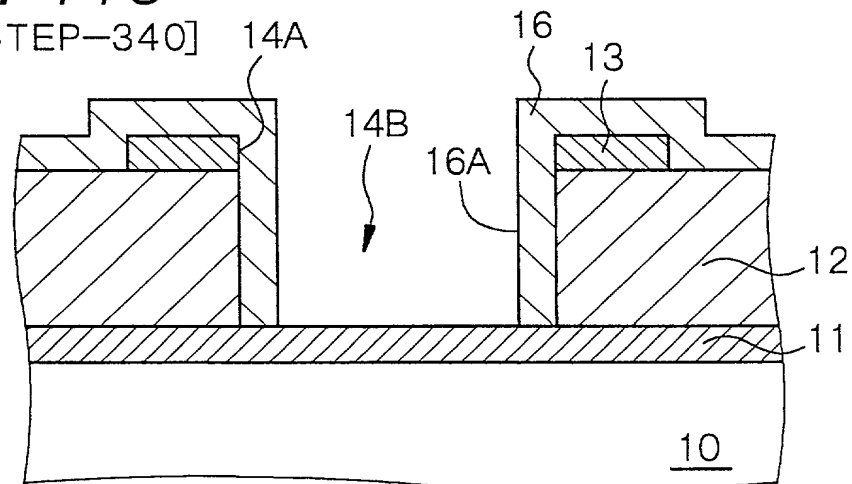


Fig. 12

[STEP-350]

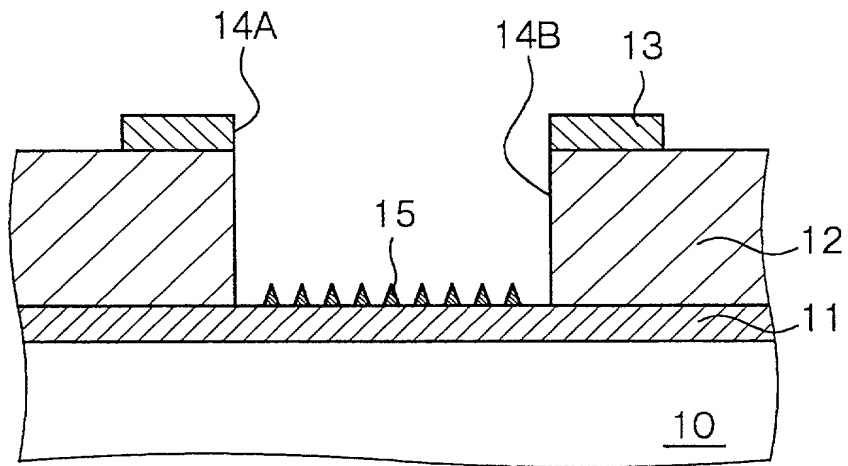


Fig. 13

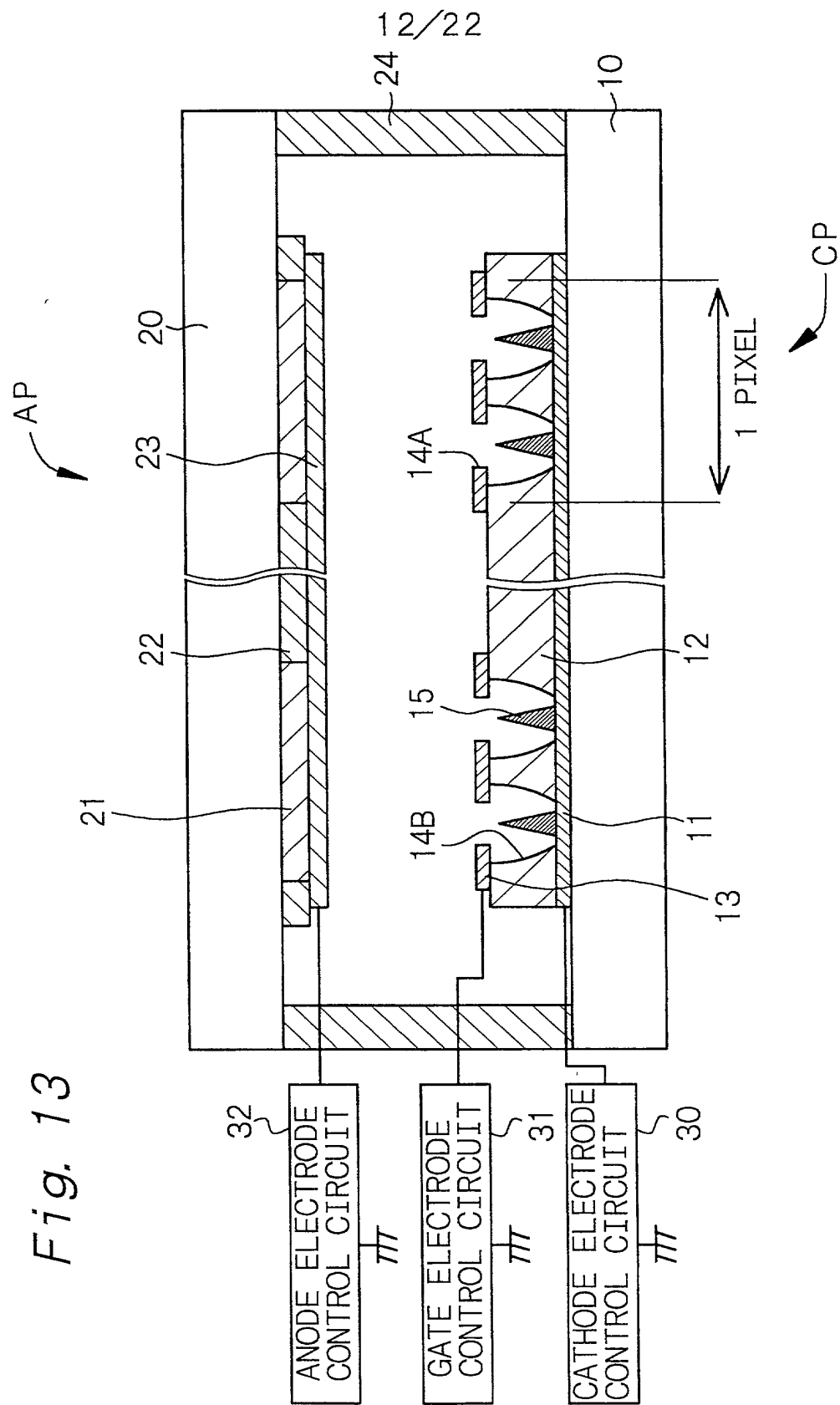


Fig. 14

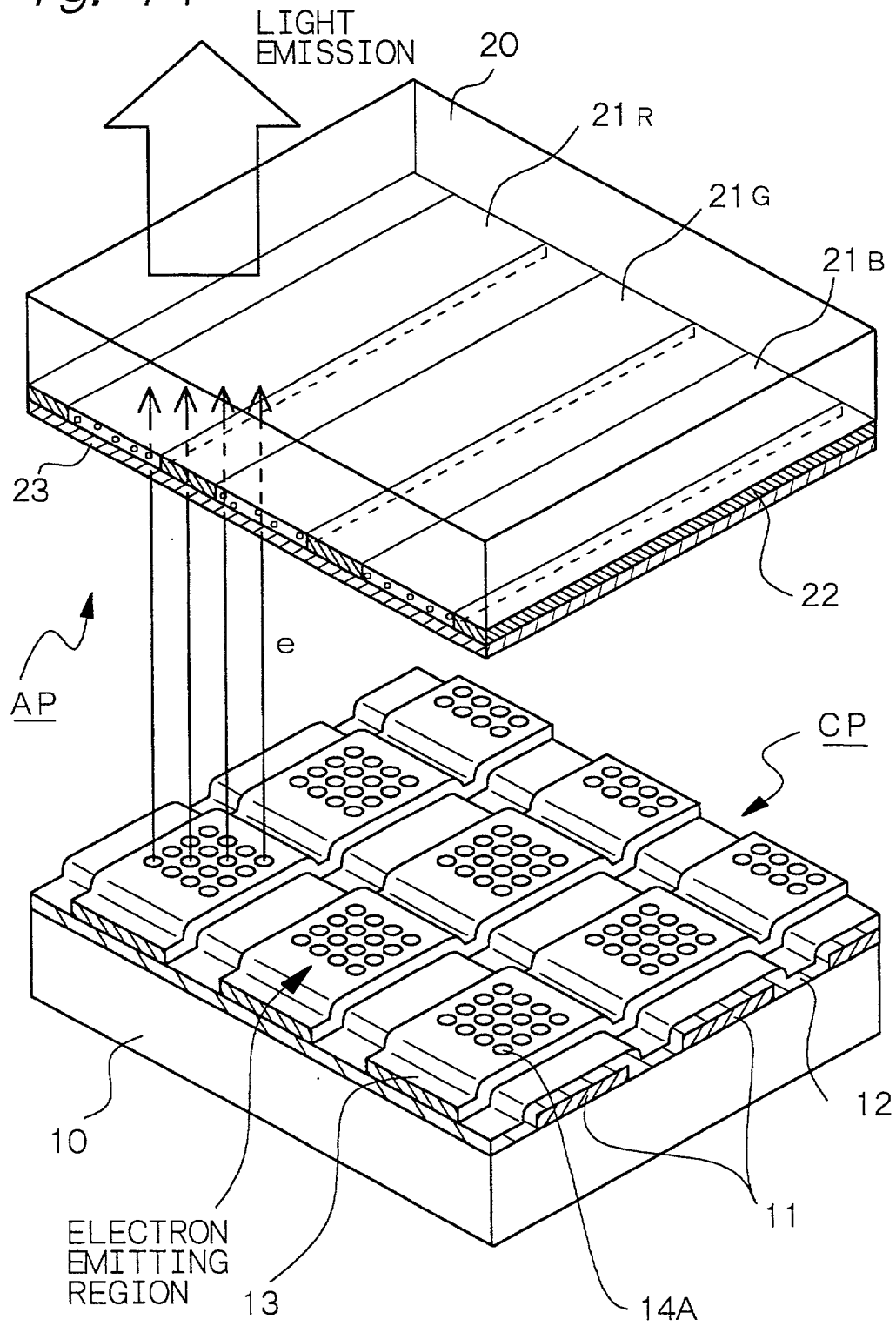
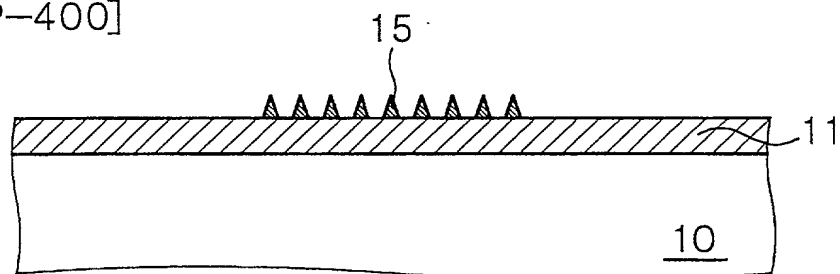
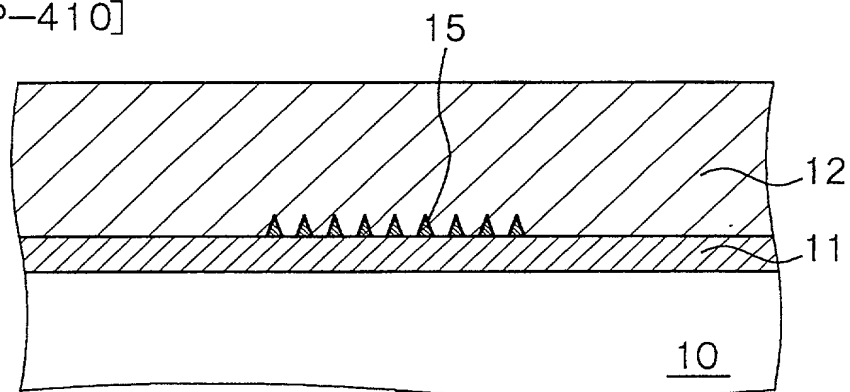


Fig. 15A

[STEP-400]

*Fig. 15B*

[STEP-410]

*Fig. 15C*

[STEP-430]

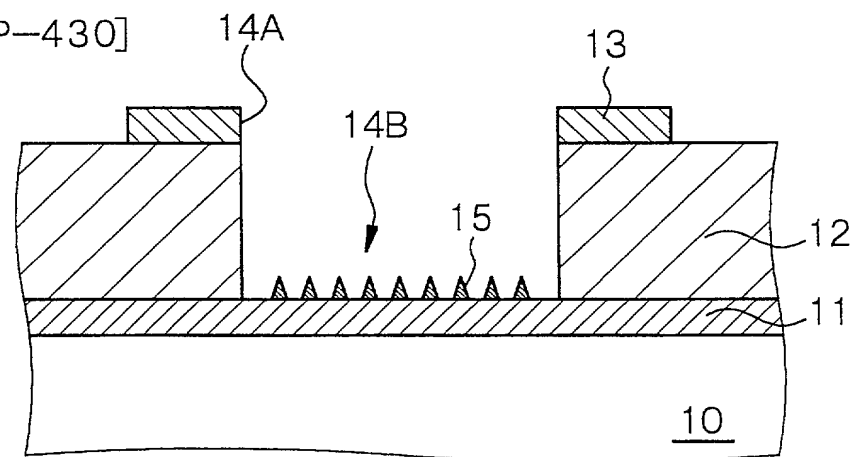


Fig. 16A

[STEP-500]

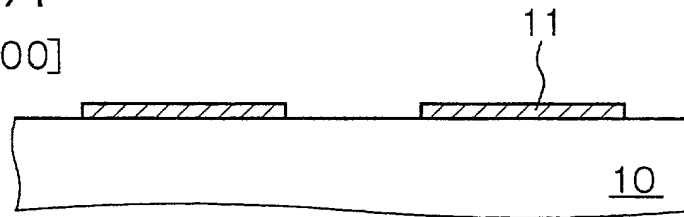


Fig. 16B

[STEP-510]

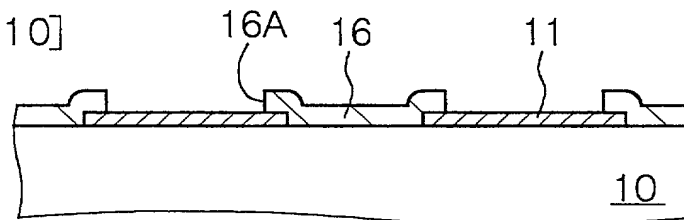


Fig. 16C

[STEP-520]

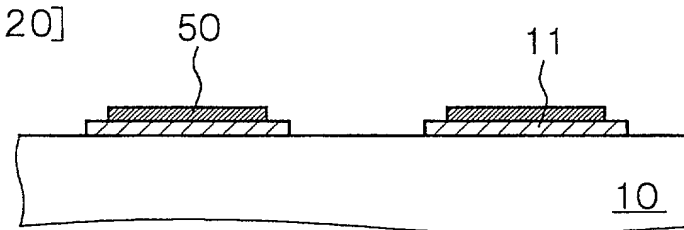
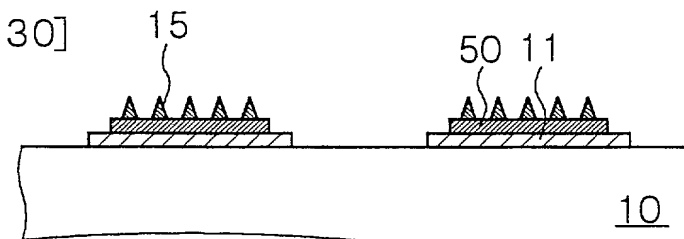


Fig. 16D

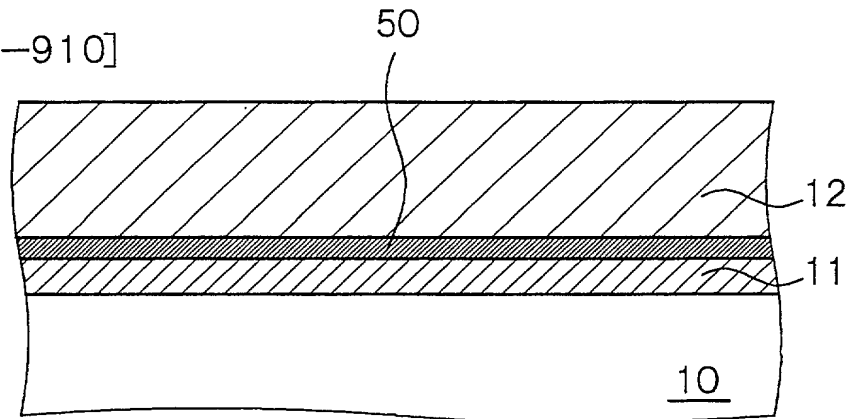
[STEP-530]



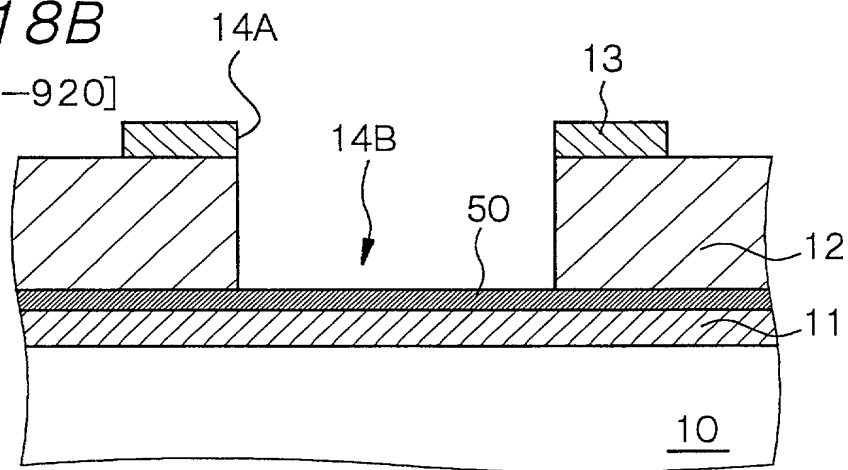
A cross-sectional view of a semiconductor device. A substrate 10 is shown at the bottom. A thin layer 11 is formed on the substrate. A layer 12 is formed on layer 11. A central region 15 is formed in layer 12, containing a series of small, upward-pointing structures. Two side regions 14A and 14B are formed on either side of region 15. Each side region 14A and 14B contains a small, rectangular structure 13. A dashed line 50 indicates a boundary or interface between the substrate 10 and the layer 11.

Fig. 18A

[STEP-910]

*Fig. 18B*

[STEP-920]

*Fig. 18C*

[STEP-930]

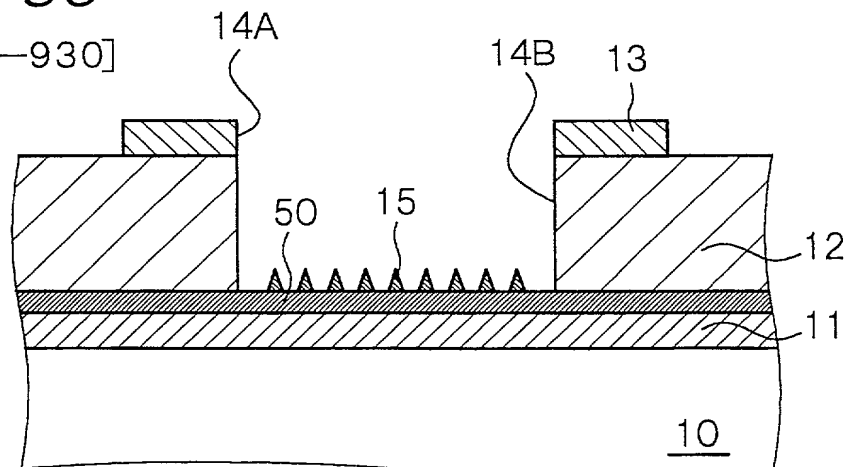


Fig. 19A

[STEP-1010]

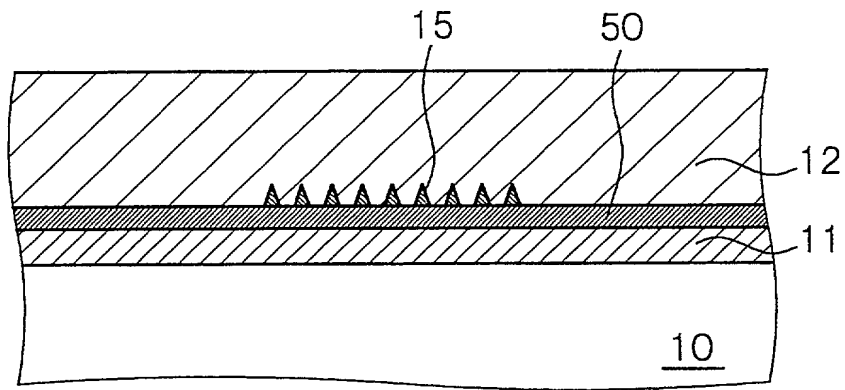


Fig. 19B

[STEP-1030]

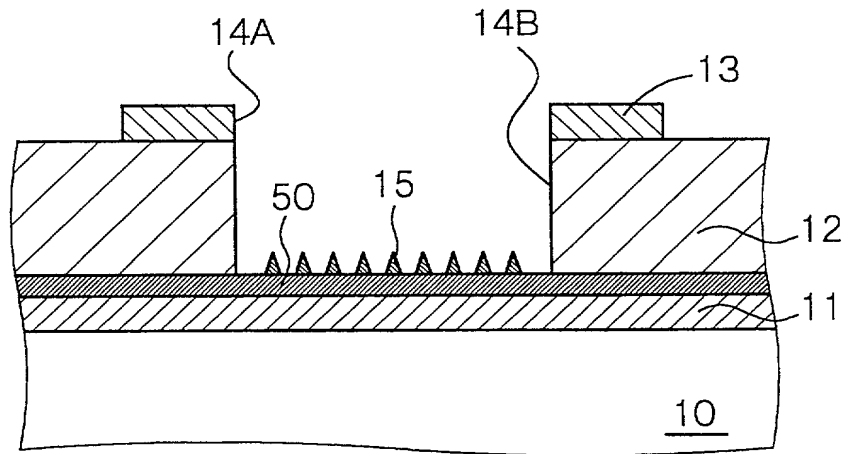


Fig. 20

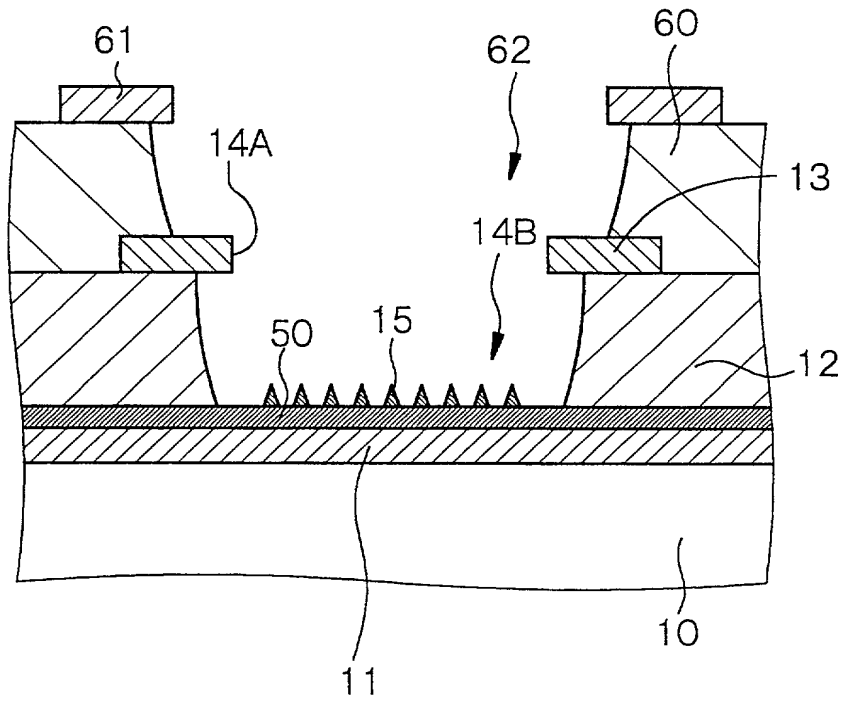


Fig. 21

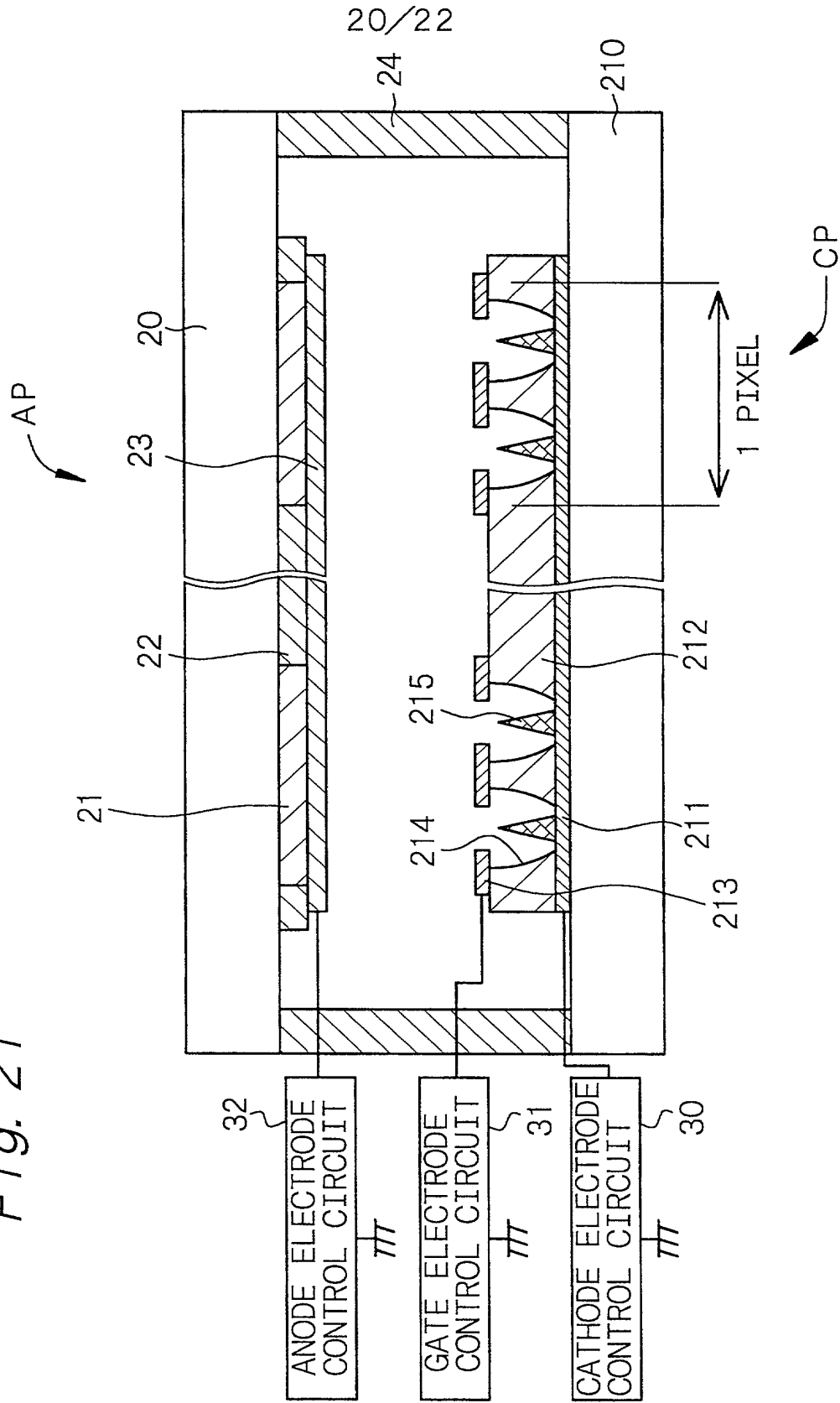
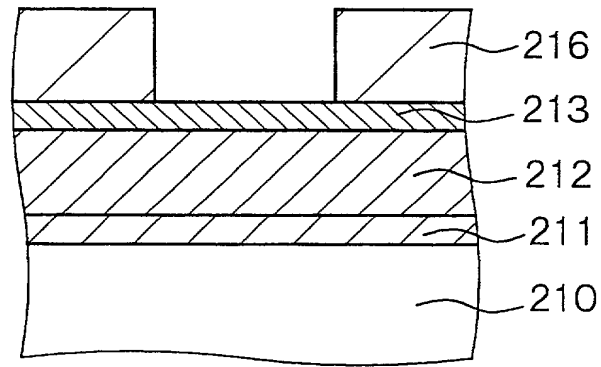
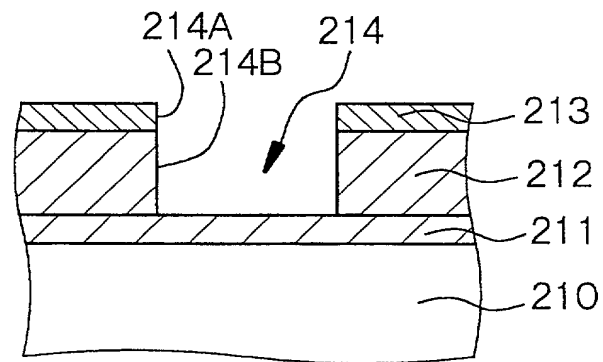


Fig. 22A

[STEP-20]

*Fig. 22B*

[STEP-20] CONTINUED

*Fig. 22C*

[STEP-30]

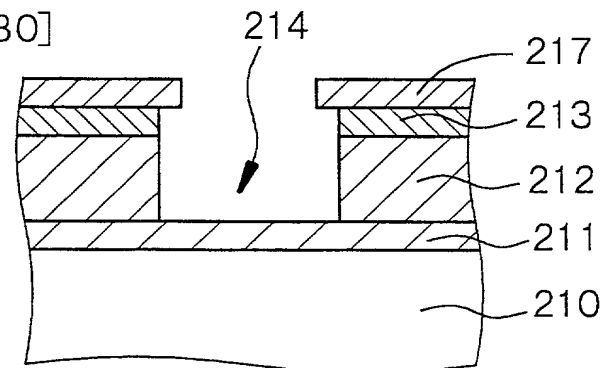


Fig. 23A

[STEP-40]

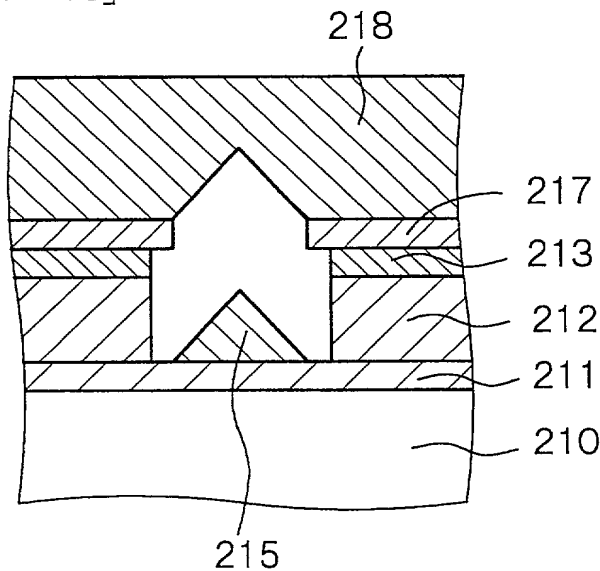


Fig. 23B

[STEP-50]

